

L Number	Hits	Search Text	DB	Time stamp
-	0	substrate and "amorphous silicon" and "optical layer" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:34
-	73	substrate and "amorphous silicon" and optical and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:35
-	2	substrate and "amorphous silicon" and optical and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon and pattern\$8 and mask and (anisotropic near4 etch) and (silicon near4 nitride)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:48
-	94	substrate and "amorphous silicon" and optical and "silicon nitride" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:49
-	54	substrate and "amorphous silicon" and optical and "silicon nitride" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:49
-	24	substrate and "amorphous silicon" and optical and "silicon nitride" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon and (pattern near4 mask)	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:50
-	0	substrate and "amorphous silicon" and optical and "silicon nitride" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon and (pattern near4 mask) and "anisotropic etch"	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:51
-	7	substrate and "amorphous silicon" and optical and "silicon nitride" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon and (pattern near4 mask) and "anisotropic"	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:52
-	6	substrate and "amorphous silicon" and optical and "silicon nitride" and reflect\$8 and (laser near4 anneal\$4) and molten and crystal\$8 and polysilicon and (pattern near4 mask) and "anisotropic" and "silicon oxide"	USPAT; US-PGPUB; EPO; JPO; DERWENT	2004/09/16 12:52